



UNITED STATES PATENT AND TRADEMARK OFFICE

UNITED STATES DEPARTMENT OF COMMERCE
 United States Patent and Trademark Office
 Address: COMMISSIONER FOR PATENTS
 P.O. Box 1450
 Alexandria, Virginia 22313-1450
 www.uspto.gov



Bib Data Sheet

CONFIRMATION NO. 4946

SERIAL NUMBER 10/660,151	FILING DATE 09/11/2003 RULE	CLASS 438	GROUP ART UNIT 2812	ATTORNEY DOCKET NO. 004994 ALRT/ETCH/SILICON
-----------------------------	---------------------------------------	--------------	------------------------	---

APPLICANTS

Songlin Xu, Fremont, CA;
 Thorsten B. Lill, Santa Clara, CA;
 Yeager Arthur Chen, Fremont, CA; Mohit Jain, San Jose, CA;
 Nicolas Gani, Milpitas, CA;
 Shing-Li Sung, Hsin-Chu, TAIWAN;
 Jitske K. Kretz, San Jose, CA;
 Meihua Shen, Fremont, CA;
 Farid Aboomeri, Pleasanton, CA;

** CONTINUING DATA *****
 This appln claims benefit of 60/444,340 01/31/2003 *AC*

** FOREIGN APPLICATIONS *****
none, of

IF REQUIRED, FOREIGN FILING LICENSE GRANTED
 ** 12/05/2003

Foreign Priority claimed <input type="checkbox"/> yes <input checked="" type="checkbox"/> no	STATE OR COUNTRY CA	SHEETS DRAWING 7	TOTAL CLAIMS 20	INDEPENDENT CLAIMS 2
35 USC 119 (a-d) conditions met <input type="checkbox"/> yes <input checked="" type="checkbox"/> no <input type="checkbox"/> Met after Allowance				
Verified and Acknowledged	Examiner's Signature <i>[Signature]</i>	Initials <i>[Initials]</i>		

ADDRESS
 44182
 MOSER, PATTERSON & SHERIDAN, LLP
 APPLIED MATERIALS INC
 595 SHREWSBURY AVE
 SUITE 100
 SHREWSBURY, NJ
 07702

TITLE
 Process for etching polysilicon gates with good mask selectivity, critical dimension control, and cleanliness